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## **Characterization of photoresist films exposed to high-dose implantation conditions**

Marion Croisy, Erwine Pargon, Cécile Jenny, Claire Richard more...

Journal of Vacuum Science & Technology B, Nanotechnology and Microelectronics: Materials, Processing, Measurement, and Phenomena **36**, 011201 (2018); <https://doi.org/10.1116/1.5004127>

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## **Low temperature bonding of heterogeneous materials using Al<sub>2</sub>O<sub>3</sub> as an intermediate layer**

Hitesh Kumar Sahoo, Luisa Ottaviano, Yi Zheng, Ole Hansen more...

Journal of Vacuum Science & Technology B, Nanotechnology and Microelectronics: Materials, Processing, Measurement, and Phenomena **36**, 011202 (2018); <https://doi.org/10.1116/1.5005591>

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## **Simultaneous molecular beam epitaxy growth at multiple uniform substrate temperatures**

Brelon J. May, and Roberto C. Myers

Journal of Vacuum Science & Technology B, Nanotechnology and Microelectronics: Materials, Processing, Measurement, and Phenomena **36**, 011203 (2018); <https://doi.org/10.1116/1.5008523>

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## **Realizing ferroelectric Hf<sub>0.5</sub>Zr<sub>0.5</sub>O<sub>2</sub> with elemental capping layers**

Yuh-Chen Lin, Felicia McGuire, and Aaron D. Franklin

Journal of Vacuum Science & Technology B, Nanotechnology and Microelectronics: Materials, Processing, Measurement, and Phenomena **36**, 011204 (2018); <https://doi.org/10.1116/1.5002558>

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## **Time multiplexed deep reactive ion etching of germanium and silicon—A comparison of mechanisms and application to x-ray optics**

Vincent J. Genova, David N. Agyeman-Budu, and Arthur R. Woll

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## **10 MeV proton damage in $\beta$ -Ga<sub>2</sub>O<sub>3</sub> Schottky rectifiers**

Jiancheng Yang, Zhiting Chen, Fan Ren, S. J. Pearton more...

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## **Improved $a$ -B<sub>10</sub>C<sub>2+x</sub>H<sub>y</sub>/Si p-n heterojunction performance after neutron irradiation**

George Glenn Peterson, Qing Su, Yongqiang Wang, Natale J. Ianno more...

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## **Assessing the manufacturing tolerances and uniformity of CMOS compatible metamaterial fabrication**

Katherine M. Musick, Joel R. Wendt, Paul J. Resnick, Michael B. Sinclair more...

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## **Energy Conversion and Storage Devices**

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### **Effects of nanowire size and geometry on silicon nanowire array thin film solar cells**

Martin Müller, Martin Ledinský, Jan Kočka, Antonín Fejfar more...

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### **Silicon-carbon composites for lithium-ion batteries: A comparative study of different carbon deposition approaches**

Alejandro Alvarez Barragan, Giorgio Nava, Nicole J. Wagner, and Lorenzo Mangolini

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Levi Bourke, and Richard J. Blaikie

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### **Nanostructures formed by the surface self-assembly of 4-(chloromethyl)phenyltrichlorosilane studied with selected solvents and temperatures**

Phillip C. Chambers, and Jayne C. Garno

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Haitao Wang, Wanyi Xie, Yunjiao Wang, Jifeng Zhu more...

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## **Mitigating e-beam-induced hydrocarbon deposition on graphene for atomic-scale scanning transmission electron microscopy studies**

Ondrej Dyck, Songkil Kim, Sergei V. Kalinin, and Stephen Jesse

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## **Analytical study of polymer deposition distribution for two-dimensional trench sidewall in low-k fluorocarbon plasma etching process**

Sun-Woo Kim, Hwan-Jun Zang, June Park, Gwang-Sik Kim more...

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## **MEMS & NEMS**

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## **Numerical and experimental thermal analysis of polyimide-based x-ray masks at the Canadian Light Source**

Sven Achenbach, Chen Shen, and Garth Wells

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## Microelectronic & Nanoelectronic Devices

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### **Frequency dispersion and dielectric relaxation in postdeposition annealed high- $\kappa$ erbium oxide metal–oxide–semiconductor capacitors**

Robin Khosla, and Satinder K. Sharma

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### **Extreme-low $k$ porous pSiCOH dielectrics prepared by PECVD**

Han You, Petra Mennell, Matthew Shoudy, Devika Sil more...

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### **Realization of a high vacuum evaporation system for wavelength shifter deposition on photo-detector windows**

Maurizio Bonesini, Roberto Mazza, Tommaso Cervi, Alessandro Menegolli more...

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## **Two-beam interference patterning of biodegradable magnesium alloy: Influence of number of passes and spots overlap**

Valentina Furlan, Marco Biondi, Ali Gökhan Demir, Barbara Previtali more...

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## **Preliminary study of a fast massive gas injection system for plasma disruption mitigation**

Gerardo D'Elia, Antonio Frattolillo, Massimiliano Bucci, and Filippo Gravanti

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## **Optical and electrical characterizations of graphene nanoplatelet coatings on low density polyethylene**

Mariano Palomba, Angela Longo, Gianfranco Carotenuto, Ubaldo Coscia more...

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## **Effect of alumina coatings on corrosion protection of steels in molten lead**

Espedito Vassallo, Matteo Pedroni, Valentina Spampinato, Silvia Maria Deambrosis more...

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### **3D-printed microfluidics on thin poly(methyl methacrylate) substrates for genetic applications**

Valentina Bertana, Cristina Potrich, Giorgio Scordo, Luciano Scaltrito more...

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### **Bacteria inactivation by atmospheric pressure plasma jet treatment**

Matteo Pedroni, Stefano Morandi, Tiziana Silvetti, Anna Cremona more...

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### **Innovative metallic solutions for alpine ski bases**

Francesco Ripamonti, Valentina Furlan, Ali G. Demir, Barbara Previtali more...

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